

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination MAGOSHI ET AL.	
		Examiner Zia R. Hashmi	Art Unit 2881	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,051,598	09-1991	Ashton et al.	250/492.2
	B	US-6,499,003	12-2002	Jones et al.	703/6
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Murai et al., "Method for Fabrication of Patterns and Semiconductor Devices", Pub> No: US 2003/0093767 A1, publication date: May 15, 2003.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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